

Beginning with the survey year 2003, the Census Bureau plans to reduce the number of detailed industries for which the ASM estimates are published. Reducing the level of detail for which characteristics are estimated will allow the Census Bureau to focus resources on improving other aspects of the ASM program. We believe that this reduction in ASM detail will not have a substantial adverse impact upon the public. While some industry detail will be lost for ASM, similar data for some of the variables are available from other sources, such as County Business Patterns or programs of the Bureau of Labor Statistics. The ASM is conducted as a mail-out/mail-back survey. No changes in the collection of information are planned as a result of this proposal.

Published estimates from the ASM are used by a variety of private business and trade associations. They provide various governmental agencies with a tool to evaluate economic policy and to measure progress toward established goals. For example, Bureau of Economic Analysis staff use data to develop nonresidential fixed investment components of gross private domestic investment in the gross domestic product. The Federal Reserve Board uses the data to estimate indexes of production, which are presented to the Board of Governors and have an impact on monetary policy.

Paperwork Reduction Act

Notwithstanding any other provision of law, no person is required to respond to, nor shall a person be subject to a penalty for failure to comply with, a collection of information subject to requirements of the Paperwork Reduction Act (PRA), unless that collection of information displays a current valid Office of Management and Budget (OMB) control number. In accordance with the PRA, 44 U.S.C. chapter 35, the OMB approved the current ASM under OMB Control Number 0607-0449. The total burden hours associated with OMB Control Number 0607-0449 are 187,000 hours. We will provide copies of each form upon written request to the Director, U.S. Census Bureau, Washington, DC 20233-0001.

Dated: May 19, 2004.

Charles Louis Kincannon,

Director, Bureau of the Census.

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DEPARTMENT OF COMMERCE

International Trade Administration

Case Western Reserve University, et al.; Notice of Consolidated Decision on Applications for Duty-Free Entry of Scientific Instruments

This is a decision consolidated pursuant to section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5 p.m. in Suite 4100W, Franklin Court Building, U.S. Department of Commerce, 1099 14th Street, NW., Washington, DC.

Comments: None received. *Decision:* Approved. No instrument of equivalent scientific value to the foreign instruments described below, for such purposes as each is intended to be used, is being manufactured in the United States.

Docket Number: 03-053. *Applicant:* Case Western Reserve University, Cleveland, OH 44106. *Instrument:* Scanning Near-Field Optical Microscope, Model ALPHASNOM. *Manufacturer:* WITEC, Germany. *Intended Use:* See notice at 69 FR 26074, May 11, 2004. *Reasons:* The foreign instrument provides: (1) The ability to perform tapping mode AFM imaging simultaneously with near field imaging, (2) > 200 nm bandwidth in the illuminating light source without having to change the near-field aperture and (3) performance of reflection mode confocal microscopy using a range of upper objectives. Advice received from: The National Institutes of Health, May 12, 2004.

Docket Number: 04-007. *Applicant:* Argonne National Laboratory, Argonne, IL 60439. *Instrument:* UHV STM Microscope with cryostat. *Manufacturer:* Unisoku Scientific Instruments, Japan. *Intended Use:* See notice at 69 FR 26074, May 11, 2004. *Reasons:* The foreign instrument provides: (1) An operating temperature of 1.8 °K, (2) *in situ* surface cleaving, (3) double stage mechanical damping and (4) a magnetic field to 7.0 Tesla. Advice received from: The National Institute of Standards and Technology, May 17, 2004.

Docket Number: 04-008. *Applicant:* California Institute of Technology, Pasadena, CA 91125. *Instrument:* Dual Beam SEM/FIB System, Model Nova 600 Nanolab. *Manufacturer:* FEI Company, the Netherlands. *Intended Use:* See notice at 69 FR 26074, May 11, 2004. *Reasons:* The foreign instrument provides: (1) Operation in high and low

vacuum, with high and low energy electrons, (2) ability to work with both thick and thin samples and (3) laser interferometer capability. Advice received from: Sandia National Laboratories, February 12, 2004 (comparable case).

Docket Number: 04-009. *Applicant:* University of Colorado, Boulder, CO 80303. *Instrument:* Cryogenic Fabry-Perot Etalon Controller (accessory). *Manufacturer:* IC Optical Systems Ltd., United Kingdom. *Reasons:* This is a compatible accessory for an existing instrument purchased for use by the applicant. It is pertinent to the intended uses and we know of no domestic accessory which can be readily adapted to the previously imported foreign instrument.

The capabilities of each of the foreign instruments described above are pertinent to each applicant's intended purposes and we know of no other instrument or apparatus being manufactured in the United States which is of equivalent scientific value to any of the foreign instruments.

Gerald A. Zerdy,

Program Manager, Statutory Import Programs Staff.

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DEPARTMENT OF COMMERCE

International Trade Administration

The Jackson Laboratory; Notice of Decision on Application for Duty-Free Entry of Electron Microscope

This decision is made pursuant to section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5 p.m. in Suite 4100W, Franklin Court Building, U.S. Department of Commerce, 1099 14th Street, NW., Washington, DC.

Docket Number: 04-006. *Applicant:* The Jackson Laboratory, Bar Harbor, ME 04609. *Instrument:* Electron Microscope, Model JEM-1230 (HC). *Manufacturer:* JEOL Ltd., Japan. *Intended use:* See notice at 69 FR 26074, May 11, 2004. *Order Date:* December 30, 2003.

Comments: None received. *Decision:* Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as the instrument is intended to be used, was being manufactured in the United States at the time the instrument was ordered. *Reasons:* The foreign instrument is a conventional transmission electron